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**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Tsuyoshi NISHIZAWA

Group Art Unit: 1722

Application No.: 10/561,957

Examiner: S. MALEKZADEH

Filed: December 22, 2005

Docket No.: 126273

For: METHOD FOR PRODUCING SILICON EPITAXIAL WAFER AND SILICON  
EPITAXIAL WAFER

**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the April 3, 2007 Office Action, please consider the following:

**Amendments to the Claims** as reflected in the listing of claims; and

**Remarks.**